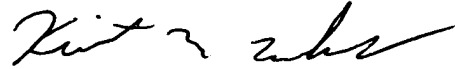


If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/5975.P2/KMT.

Respectfully submitted,



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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet

1

of

2

Application Number

10/811,230

Filing Date

March 26, 2004

First Named Inventor

Ganguli, et al.

Group Art Unit

1762

Examiner Name

Unknown

Attorney Docket Number

AMAT/5975.P2/CPI/L/B/PJS

Submission Date

September 20, 2004

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	A1	US-6713373	03/30/2004	Omstead	
	A2	US-6617634	09/09/2003	Marsh, et al.	
	A3	US-6610568	08/26/2003	Marsh, et al.	
	A4	US-6605735	08/12/2003	Kawano, et al.	
	A5	US-6596602	07/22/2003	Iizuka, et al.	
	A6	US-6580111	06/17/2003	Kim, et al.	
	A7	US-6527855	03/04/2003	De La Rosa, et al.	
	A8	US-6482740	11/19/2002	Soininen, et al.	
	A9	US-6479100	11/12/2002	Jin, et al.	
	A10	US-6440495	08/27/2002	Wade, et al.	
	A11	US-6423619	07/23/2002	Grant, et al.	
	A12	US-6462367	10/08/2002	Marsh, et al.	
	A13	US-6365502	04/02/2002	Paranjpe, et al.	
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	A19	US-20020173054	11/21/2002	Kim	
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	A22	US-20020102810	08/01/2002	Iizuka, et al.	
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	A26	US-20020028556	03/07/2002	Marsh, et al.	
	A27	US-20020025627	02/28/2002	Marsh, et al.	
	A28	US-20020004293	01/10/2002	Soininen, et al.	

Examiner

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Sheet 2

of 2

Application Number	10/811,230
Filing Date	March 26, 2004
First Named Inventor	Ganguli, et al.
Group Art Unit	1762
Examiner Name	Unknown
Attorney Docket Number	AMAT/5975.P2/CPI/L/B/PJS
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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	A29	US-20020000587	01/03/2002	Kim, et al.	
	A30	US-20010054730	12/27/2001	Kim, et al.	
	A31	US-20010006838	07/05/2001	Won, et al.	

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		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
	B1	WO 01/88972	11/22/2001			
	B2	JP 2001-237400	08/31/2001			
	B3	JP 2001-111000	04/20/2001			

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
	C1	Aaltonen, <i>et al.</i> , "Atomic Layer Deposition of Ruthenium from RuCp ₂ and Oxygen: Film Growth and Reaction Mechanism Studies," Electrochemical Society Proceedings Volume 2003-08 pp. 946-953.	
	C2	Aaltonen, <i>et al.</i> , "Atomic Layer Deposition of Ruthenium Thin Films from Ru(thd) ₃ and Oxygen," Chem. Vap. Deposition (2004), 10, No. 4 pp. 215-219.	
	C3	Aaltonen, <i>et al.</i> , "Ruthenium Thin Films Grown by Atomic Layer Deposition," Chem. Vap. Deposition (2003), 9, No.1 pp.45-49.	
	C4	Aoyama, <i>et al.</i> , "Ruthenium Films Prepared by Liquid Source Chemical Vapor Deposition Using Bis-(ethylcyclopentadienyl)ruthenium," Jpn. J. Appl. Phys. Vol. 38 (1999) pp. L1134-L1136.	
	C5	Dadgar, <i>et al.</i> , "Growth of Ru doped semi-insulating InP by low pressure metalorganic chemical vapor deposition," Journal of Crystal Growth 195 (1998) pp. 69-73.	
	C6	Kwon, <i>et al.</i> , "Atomic Layer Deposition of Ruthenium Thin Films for Copper Glue Layer," Journal of the Electrochemical Society, 151 (2) (2004) pp. G109-G112.	
	C7	Kwon, <i>et al.</i> , "Plasma-Enhanced Atomic Layer Deposition of Ruthenium Thin Films," Electrochemical and Solid-State Letters, 7 (4) (2004) pp. C46-C48.	
	C8	Lashdaf, <i>et al.</i> , "Deposition of palladium and ruthenium β -diketonates on alumina and silica supports in gas and liquid phase," Applied Catalysis A: General 241 (2003) pp. 51-63.	
	C9	Lim, <i>et al.</i> , "Atomic layer deposition of transition metals," Nature Materials, Vol. 2 November (2003) pp. 749-754.	
	C10	Shibutami, <i>et al.</i> , "A Novel Ruthenium Precursor for MOCVD without Seed Ruthenium Layer," TOSOH Research & Technology Review, Vol. 47 (2003) pp. 61-64.	

Examiner

Date Considered

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